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#### **PROFESSIONAL SUMMARY**

Extensive experience in R&D, R&D leadership, line management, and strategic planning. As Director of the Reactor and Nuclear Systems Division at the Oak Ridge National Laboratory (ORNL), responsible for the strategic direction of the organization and for supporting the mission areas of the U.S. Department of Energy and ORNL. Has experience developing and leading multiple research organizations of Ph.D.- and M.S.-level scientists, engineers, technical, and business staff in support of important national science and engineering initiatives in nuclear and non-nuclear energy research. Over 17 years of Group Leadership and 8 years of Division Leadership creating novel science and engineering concepts and programs requiring scientific research, technology development and maturation, technology transfer and licensing, contract negotiation, program execution, staffing, and mentoring. Experience teaming and forming productive partnerships and collaborations with national and international organizations. Ideally suited to lead a complex, multi-faceted research organization working in energy research across areas of high-performance computing for modeling and simulation of complex energy systems, and instrumentation and controls supporting advanced research in nuclear energy, renewables, grid modernization, energy efficiency, resiliency, and national security.

#### EDUCATION

 Ph.D. Nuclear Engineering, University of Virginia, Charlottesville, Virginia, 1987. Dissertation: Digital Filtering and Reconstruction of Coded Aperture Images.
M.S. Nuclear Engineering, Virginia Polytechnic Institute and State University, Blacksburg, Virginia, 1984. Thesis: Iodine Spiking in Pressurized Water Reactors.

**B.S.** Physics, Virginia Polytechnic Institute and State University, Blacksburg, Virginia, 1983.

#### **RESEARCH EXPERIENCE**

Photonics, neutronics, x-ray, SEM, electronic imaging and microscopy coupled with signal processing and machine learning research to address problems of energy, security, and human health. Science and technology specialty in computational imaging, image metrology, object segmentation, and feature generation from multi-spectral, multi-source imagery for inverse imaging (e.g., computed tomography and coded image recovery), robust human-level classifiers, image archival and retrieval applications, and image-based informatics. Primary interest is in the novel application of computer vision science, methods, and technologies to the solution of real-world problems in industry, security, and biomedicine. Was designated an ORNL Corporate Research Fellow in 2003 for *outstanding contributions to the field of applied computer vision research and development*. Designation as a Corporate Fellow is made on a limited basis to recognize exceptionally gifted individuals at ORNL for their technical achievement in science or engineering. Of the over 4,500 staff at ORNL today, there are about 30 active Corporate Research Fellows.

### **EMPLOYMENT HISTORY**

# **2017-Present**, Oak Ridge National Laboratory, Oak Ridge, Tennessee **Director / Corporate Research Fellow**, Reactor and Nuclear Systems Division (RNSD)

• **Division Director** – Director of the RNSD Division (October, 2016). Providing science and technology leadership and strategies for the US. DOE/NE, Nuclear Regulatory Commission (NRC) and U.S. Industry in support of advanced reactor technology and systems, reactor physics and thermal hydraulics modeling and simulation, radiation transport, nuclear criticality and safety, and used fuel systems. RNSD provides the S&T required to extend the life of our existing light water reactor fleet, create advanced concepts for small modular and molten salt reactors for next generation power production, develop proliferation resistant nuclear fuel cycles, and modernize the nuclear regulatory infrastructure.

### 2013-2016, Oak Ridge National Laboratory, Oak Ridge, Tennessee

Director / Corporate Research Fellow, Electrical and Electronics Systems Research (ESSR) Division

- **Division Director** Founding Director of the EESR Division (October, 2013). Led the organizational change to integrate the electronics research capabilities of the Energy and Environmental Science Directorate into a single division to address R&D in microelectronics, embedded electronics, power electronics, and power systems. EESR was positioned to better support the U.S. Department of Energy (DOE) in the design and test of wide-bandgap materials; development and evaluation of electric vehicle components; electric grid and cyber-physical systems; building sensors and controls; building/grid integration; nuclear energy instrumentation; and national nuclear security. These changes enhance EESR's ability to achieve nationally important impact through applied, cross-cutting research in electronics, sensors, signal analysis, communications, and controls. The division was primarily funded through WFO when established in 2008. Between 2008 and 2016, strategy and leadership achieved an R&D portfolio mix of 62% DOE, 33% WFO, and 5% LDRD, making EESR of high relevance to the missions of the U.S. DOE.
- Building a Strong DOE Research Portfolio (2016, \$61M Budget Authority, \$14M Sold Services) The EESR Division provided the science and technology underpinnings in electronics, sensors, and controls for a number of important cross-cutting program areas for the directorate and the lab such as: low-cost sensors for characterizing and controlling energy use in commercial buildings (EERE/BTO); additive manufacturing sensing for control and analytics for advanced manufacturing (EERE/AMO); small form-factor 3D-printed inverters for electric vehicles (EERE/VTO); embedded sensing and control system for the Macromolecular Neutron Diffractometer with SNS (BES); application of neutrons and the VENUS imaging instrument to characterize materials in manufacturing and vehicle technology (EERE/AMO, BES); microwave guide inspection tool for ITER; computed tomography for gas well casements (EERE/GTO); key support for the development of sensors and controls for the Molten Salt Test Loop experiment (NE); and a significant increase in programmatic collaboration and S&T responsibility for the Domestic Uranium Enrichment program (NNSA), and the stable isotopes program (BES).
- Creating Internet-of-Things (IoT) Research Opportunities (2015, \$3.2M LDRD, \$300K Discretionary Investment) – Established a successful approach to invest discretionary funding and achieve LDRD and Seed awards that are fueling a number of important programmatic opportunities in IoT research. EESR is leading the efforts for ORNL on the Grid Modernization Lab Consortium in Sensing and Measurement activities (EERE/OE/EPSA); partners on a national team for the Smart Manufacturing National Network for Manufacturing

Innovation (EERE/AMO); organizing a national proposal team to address spectrum sharing through the Model City opportunity (FCC/NTIA); and creating a connected vehicle and vehicle security initiative that resulted in a \$600K lab investment at NTRC for a Vehicle Security Laboratory (EERE/VTO, DOT, DOD).

# 2009-2015, Hubble Telemedical, Inc., Memphis, Tennessee

**Founder and Chief Technology Officer** for Hubble Telemedical, Inc. Co-inventor of Hubble's patented telemedical diagnosis network technology to provide low-cost, high-throughput retinal screening. The technology was created to help save the sight of diabetic patients, particularly those with low incomes and a lack of access to regular vision screenings.

• **Hubble Telemedical's corporate objectives** were to demonstrate scalability and adoption of the company's disruptive technology into the medical care and managed care spaces and demonstrate that the revenue generated by its telemedical network can be scaled regionally, nationally, and internationally into a successful business model. The Hubble technology was licensed from UT-Battelle, LLC, in 2009. Dr. Tobin supported the commercial venture through an Outside Activity agreement with ORNL. Hubble achieved venture capital investment by **Memphis Biomed Ventures** in 2010 and was acquired by New York company, **Welch Allyn Inc.**, in January 2015. Welch Allyn is a leading medical diagnostic device company that delivers practical innovation at the point of care. Hubble Telemedical translated semiconductor yield analysis technology to a venture capitalized C-Corp., to acquisition by Welch Allyn in seven years and is providing retinal health care to many thousands of patients nationwide, improving patient outcomes and reducing healthcare costs.

# 2008-2013, Oak Ridge National Laboratory, Oak Ridge, Tennessee

Director / Corporate research Fellow, Measurement Science and Systems Engineering Division

- **Division Director** Provided science and technology leadership and management for a research division of 150 R&D, business, operations staff, and students. Founding Director of the Measurement Science and Systems Engineering (MSSE) Division (March 2008). MSSE performed applied research and development in nationally important areas of energy efficiency, resilience, and security. The mission of MSSE was to provide pathways for the translation of basic science to engineering applications through the creation of foundational capabilities and technologies in electronics, sensors, signals processing, and integrated systems. The division's staff were organized into eight technology-focused research groups with science and technology competencies and capabilities that encompass the development of new electronic devices and high-performance embedded computing, new sensors and sensing materials, signal processing and machine learning methods, robust wireless communications, and the integration of these technologies into unique systems and instruments that address challenging measurement and controls problems.
- Neutron Imaging Instrument at SNS for Energy Efficiency (2011-2016, \$19M) Co-Developer and instrument advocate for the design, development, and commissioning of a world-class neutron imaging instrument designated the Versatile Neutron Imaging Instrument at SNS (VENUS). VENUS will uniquely utilize the Spallation Neutron Source (SNS) to measure and characterize large-scale, multi-component, engineered materials and systems. VENUS will be the highest resolution neutron imaging instrument in the world and it will provide industry with the opportunity to advance their development efforts in energy efficiency, transportation, material systems, and a wide variety of non-destructive engineering design and testing applications. VENUS will uniquely support the missions and program areas of the U.S. DOE Office of Energy Efficiency and Renewable Energy (EERE) and the Office of Electricity Delivery and Energy Reliability (OE).
- Automated Screening for Diabetic Retinopathy by Content (2009-2011, \$2.2M) Co-developer with the University of Tennessee Health Science Center, Memphis, TN, of a competitive renewal for National Institute of Health (NIH) grant R-01 EY017065 with the National Eye Institute (NEI). Goal was to investigate the feasibility

of using content-based image retrieval to detect and accurately describe and index human retinal disease, specifically diabetic retinopathy, collected remotely from low-cost, non-dilated retinal photographs. Using CBIR, we have successfully developed a telemedical method and technology that permits remote diagnosis of diabetic retinopathy (DR) in the primary health care setting, in real time, through remote access to a computer-based, diagnostic, image analysis method. The studies proposed in this competitive renewal were designed to address key methods in the performance of automated machine segmentation by our current algorithms. Our goal under this renewal grant was to improve system performance to a level that permitted implementation as a fully automated patient care paradigm with expert capabilities that yields the highest possible sensitivity and specificity of disease detection and stratification.

• Novel Method to Achieve High-Resolution Neutron Microscopy (2008-2009, \$175K) – Co-developer of an ORNL Seed Money project to implement and test a unique method to achieve high-resolution neutron microscopy in the sub-5 µm resolution range using coded apertures. This is a novel configuration that encodes the source of neutrons passing through an object as opposed to an encoding of radiation emitted from an object. Project represents a partnership between MSSE, SNS, and NC State and was leveraged to establish a U.S. DOE Early Career Award for the project co-developer and PI. Successful demonstration of high-resolution neutron imaging supports our efforts to develop new instrumentation within the Neutron Sciences and Energy and Environmental Sciences Directorates that facilitates our ongoing Instrument Development Team (IDT) to establish a dedicated neutron imaging beam line at SNS.

# 2003-2008, Oak Ridge National Laboratory, Oak Ridge, Tennessee Group Leader / Corporate Research Fellow, Engineering Science & Technology Division

- **Group Leader** Provided 17 years (1991-2008) of leadership, program development, programmatic guidance, and technical direction for a talented group of Ph.D.- and M.S.-level scientists in computer vision research and development. Helped define and maintain a consistent research mission and direction for R&D activities undertaken by the group. Hired personnel, developed and mentored staff, and developed research proposals and contracts that supported the group mission and activities in three program areas: Industrial Inspection and Metrology, Biomedical Imaging, and National Security. Group Mission: *To emulate the human visual sensory and cognitive process. To develop human-level visual and decision- making capabilities for computers and robots.*
- **Participation in the NIST Iris Challenge Evaluation: Algorithms for Improving Iris Recognition (2006,** \$178K) – Co-developer and principle investigator of an Oak Ridge National Laboratory Seed Money project to perform iris segmentation and recognition research and development and to participate in the NIST Iris Challenge Evaluation (ICE). ICE was the first large-scale, open, independent technology evaluation effort for iris recognition. The primary goal of ICE was to promote the development and advancement of iris recognition technology and assess the state-of-the-art capability. Through this research we implemented and tested novel approaches for biometric iris recognition that addressed shortcomings in the current technology relating to degraded iris image quality due to off-axis viewing of the iris and the non-linear effects of pupil dilation on the iris pattern, with a goal of more efficacious evaluation of non-cooperative subjects.
- Automated Screening for Diabetic Retinopathy by Image Content (2006-2008, \$1.62M) Co-developer and co-principal investigator of this National Institute of Health (NIH) grant by the National Eye Institute (NEI) to investigate the feasibility of a content-based image retrieval (CBIR) method to accurately describe and index human retinal images of diabetic retinopathy (DR) collected from low-cost, non-dilated retinal photographic examinations. The grant was titled "Automated Screening for Diabetic Retinopathy by Content" (1 R01 EY017065-01). The goal was to demonstrate the feature-based indexing and retrieval process of CBIR and verify our hypothesis, and novel concept, that retinal pathology can be identified and stratified from visually similar

retinal images assembled from a large database comprising images of DR. This research adapted and extended an earlier CBIR method for industrial inspection and remote earth imaging by incorporating intrinsic and extrinsic human patient data to provide a diagnostic method. This grant was co-developed in partnership with the University of Tennessee Health Science Center's Hamilton Eye Institute, Memphis, Tennessee.

- **Diagnosis of Blinding Eye Disease (2004-2005, \$178K)** Developer and principle investigator of an Oak Ridge National Laboratory Seed Money project to develop a telemedicine capability for diagnosing retina-based blinding eye disease (e.g., resulting from diabetic retinopathy, macula edema, glaucoma, etc.) using a content-based image retrieval method in conjunction with a novel directed indexing concept. Established a collaborative R&D relationship with the University of Tennessee Health Science Center's Hamilton Eye Institute in Memphis, TN, to develop an extensive anonymized human patient database of diagnosed fundus, fluorescein angiography, and optical coherence tomography images.
- Confocal Coded Aperture Gamma Camera (2003, \$80K) Developer and principal investigator of this DOE NA-22 Exploratory R&D project to investigate the development of a novel coded aperture gamma imaging technology that overcomes limitations associated with historical attempts to image broadly distributed sources with coded apertures. Concept had the ability to perform high-resolution imaging of a distributed source while maintaining high collection efficiency. The initial application for this technology was to inhibit nuclear materials diversion and to support international safeguards related to activities of the International Atomic Energy Agency for LWR spent fuel verification. Participated by invitation of the IAEA as a U.S. expert on gamma imaging in a Coordinated Technical Meeting on Spent Fuel Verification Methods, held at the Vienna International Center, Vienna, Austria.
- Image to Intelligence Archive (2003-2004, \$770K) Co-developer and co-principal investigator of a Laboratory Directed R&D (LDRD) program to create a novel geographic information system (GIS) for managing, analyzing, and retrieving earth imagery gathered from satellite and aircraft. Technical contribution related to developing a Directed Indexing Library (DIL) method for succinct and adequate mapping of image region features for efficient database indexing and retrieval. The DIL method was also being applied to a fractal-based approach to segment images into functional regions (e.g., urban, forest, agricultural, etc.) prior to feature description and indexing. The archive architecture is broadly applicable to many fields where image data is collected and maintained such as biology, medical, industrial and GIS.

# <u>1999-2003, Oak Ridge National Laboratory, Oak Ridge, Tennessee</u> Group Leader / Distinguished R&D Staff Member, Engineering Science & Technology Division

- **Digital Holographic Lithographic Mask Metrology (2002-2005, \$710K)** Developer and principal investigator of a cooperative research program with International SEMATECH (Litho Metrology Program), Austin, TX. This project included a feasibility study and prototype development effort to adapt the ORNL direct-to-digital holographic microscopy technology to the area of lithographic mask metrology. The ability to directly measure the modulation of the optical phase front imparted by a lithographic mask is inherent in the interferometric approach of the direct-to-digital holography technology. Application to binary, optical proximity correction, and phase shifting masks were studied in both reflective and transmissive geometries.
- **Digital Holographic Optical Microscopy for Wafer Inspection (2000, \$1.5M, 2001-2003 NIST-ATP, \$2.4M)** - Co-developer and principal investigator of this multi-year, cooperative research program to design, build, and transfer an interferometric optical microscope technology for the inspection of high-aspect ratio structures (e.g., contacts, vias, and trenches) on semiconductor wafers. Responsibilities included coordination and development of signal and image processing tasks related to hologram reconstruction, image alignment, defect detection, and noise mitigation.
- **3D Structural Metrology for Semiconductor Lithography** (2000-2002, \$500K) Developer and principal investigator of a cooperative research program with International SEMATECH (Litho Metrology Program),

Austin, TX. This project was an extension of the Automated Image Retrieval technology to the estimation of three-dimensional sidewall structure from top-down, critical-dimension scanning electron microscopy. Method enabled semiconductor device manufacturers to reuse historical critical dimension metrology image information to estimate the shapes of critical structures during lithographic processes. This resulted in a reduced need to physically cross-section semiconductor product wafers, a time-consuming, destructive and expensive test.

Automated Image Retrieval (2000-2001, \$1.1M, 2002-2003, \$1.5M) – Developer and principal investigator of a cooperative research program with Applied Materials, Inc., Santa Clara, CA. This work evolved from the Manufacturing-specific Content-based Image Retrieval and Semiconductor Yield Analysis projects started at ORNL. Included adapting and integrating the ORNL Automated Image Retrieval (AIR) technology for managing image data in the semiconductor manufacturing environment. Cooperative agreement included negotiations resulting in a commercial license between ORNL and Applied Materials, and ORNL and International SEMATECH for the patented AIR technology.

# 1996–1999, Oak Ridge National Laboratory, Oak Ridge, Tennessee

Group Leader / Senior Research and Development Staff Member, Instrumentation & Controls Division

- Semiconductor Yield Analysis (1994-2002, \$2.7M) Developer and principal investigator of a cooperative research program with International SEMATECH (Metrology / Yield Management Tools Program), Austin, TX. This was a broad-based program to develop data analysis and data reduction technologies ranging from automatic defect classification and spatial signature analysis of patterned semiconductor wafers, to the application of content-based image retrieval technologies to semiconductor yield management. Worked closely with the semiconductor industry and suppliers of semiconductor inspection and yield management hardware and software. Developed novel (patented) electronic imaging paradigms for segmentation and pattern recognition to characterize semiconductor defects and manufacturing processes. Image modalities included optical (monochrome and color), scanning electron microscopy, digital holography, and confocal microscopy. Work culminated in 19 manufacturing and commercial licenses of the technology.
- Video Forensics for Law Enforcement (1998-2002, \$700K) Developer and principal investigator of a Department of Energy project to assist law enforcement agencies in the analysis of surveillance video data primarily associated with crime scenes. Required the integration of object tracking, motion estimation, and multi-frame fusion algorithms to improve the fidelity and resolution of facial features and text items in low-quality video data. Collaborations were established with the United States Secret Service Video and Audio Forensics Unit, ATF Video Forensics Unit, and FBI Special Photographic Unit.
- X-ray Inspection of Airport Baggage (1998-2003, \$800K) Co-developer and principal investigator of this National Safe Skies Alliance / FAA project to develop novel concepts for operator-assist software for the x-ray inspection of carry-on luggage. Technology encapsulated human expert response in a fuzzy inferencing system that resulted in a demarcation of focus-of-attention regions. Applications of the technology included fusion with other commercial technologies for explosives and threat object detection to reduce false alarms.

# <u>1991-1995, Oak Ridge National Laboratory, Oak Ridge, Tennessee</u> Group Leader / Research and Development Staff Member, Instrumentation & Controls Division

Automatic Optical and SEM Defect Classification (1992-1995, \$600K, 1997-2000, \$850K) – Co-developer of several working relationships with the U.S. semiconductor inspection and yield management industry. Programs required the design of algorithms and software systems to address defect image analysis, feature representation, and classification of both color optical and SEM imagery collected in the pre-and post-fab environment. Inspection resolution regimes are post fab optical (>5 µm), in-line optical (<0.25 µm), and off-line SEM review</li>

(<0.1 µm). Collaborative partners included Electroglas, KLA-Tencor Instruments, Applied Materials, Knights Technology, Texas Instruments, and Intel.

- **Manufacturing-specific, Content-based Image Retrieval (1998-1999, \$120K)** Developer and principal investigator of an Oak Ridge National Laboratory Seed Money project to develop a Manufacturing-specific, Content-based Image Retrieval technology for image retrieval in the industrial environment. This technology was designed to take advantage of the unique characteristics of electronic images generated during in-line and off-line inspection processes. The method incorporated an efficient O(log<sub>2</sub>(N)) approximate nearest-neighbor indexing/search structure and operator feedback to accommodate a wide variety of query scenarios. This work resulted in the creation of two patented technologies and various commercial licenses in the semiconductor industry.
- Printed Fabric Inspection and Imaging Colorimetry (1993-95, \$450K, 1998-1999, \$790K) Co-developer of the American Textile Partnership<sup>™</sup> Computer Assisted Fabric Evaluation Program to provide applied R&D for on-line quality monitoring and automation of textile production and finishing processes. Principal investigator for the development of an on-line, high-speed tri-color data collection system for monitoring rotary screen print processes for screen registration, screen flaws, and other color printing errors. Principal investigator for development of a unique color printed-pattern and imaging tristimulus colorimeter system for inspecting patterned color textile products. Colorimetric approach used adaptation of the projection onto convex sets (POCS) method to estimate reflectance spectra based on tristimulus color camera measurements.
- **Technical Ceramics Inspection** (1992-1997, \$1.1M) Co-developer of a cooperative research program with Coors Ceramics, Grand Junction, CO, and Chattanooga, TN, to automate the inspection of thick-film ceramic substrates and pre-fired patterned ceramic package components. Developed novel methods for optical defect detection and dimensional metrology of thick film ceramic components. Resulted in the development and deployment of two inspection systems, one for thick-film ceramic substrates in Grand Junction, CO, and a second for inspecting patterned substrates in Chattanooga, TN.

# <u>1987 –1991 Oak Ridge National Laboratory, Oak Ridge, Tennessee</u> Research and Development Staff Member, Applied Technology Division

- **Research Staff Member** Developed remote measurement algorithms, methods, sensors and systems relying on infra-red, optical, and ultraviolet lasers, free space optics and fiber optics, and associated electronic devices. Applications included laser induced fluorescent spectroscopic studies, high, low, and transient temperature applications of thermographic phosphor materials, remote stress/strain diagnostics, and design and characterization of fiber optic and optical based probes.
- **High-speed Inspection of U.S. Printed Currency and Postage Stamps** Developer of image processing methods for high accuracy, three-dimensional image registration (i.e., spatial x and y position plus grey-scale histogram specification) in support of off-line currency review and in-line postage stamp inspection for the U.S. Bureau of Engraving and Printing and the U.S. Postal Service. Quality control prototype systems were created to support these agencies development of commercial Requests for Proposals (RFPs).
- **Turbine Engine Thermometry** Key designer of signal processing methods to implement non-contact, spectroscopic thermography for *in-situ* turbine blade temperature analysis. Participated in the design of air-cooled, fiber optic probes to work in harsh turbine/combustor environments. Oversaw three field tests of fiber/laser delivery systems at Pratt & Whitney in Hartford, Connecticut, and Orlando, Florida, and at the Turbine Engine Test Facility at Virginia Tech, Blacksburg, Virginia.
- Vehicle Weigh-in-motion Principal developer of signal processing algorithms and methodology for implementing a compact, fiber optic-based vehicle weigh-in-motion system for highway vehicle characterization. Responsibilities included the design of algorithms to estimate vehicle weight per wheel, system calibration, and participation in field-testing.

### **PROFESSIONAL SOCIETIES / COMMITTEES / EDITOR / BOARDS**

#### **Boards / Panels**

**Roane County Chamber of Commerce**, Kingston, Tennessee – Member of the Board of Directors, July 2016 – present.

**Industrial Advisory Board (IAB),** Department of Electrical Engineering and Computer Science, University of Tennessee, Knoxville – Member of the Board, Academic Year 2012-present.

National Safe Skies Alliance, Alcoa, TN – Member, Board of Directors, 2011-present.

**FIRST Robotics Competition**, Knoxville, TN - Member, Regional Board of Directors, Competition judge, 2011-2013. Founding Mentor, Roane County High School, 2012-present.

**U.S. Department of Homeland Security** - S&T Secure Boarders Initiative, Invited Member Review Panel, Tucson, AZ, August 15-18, 2011.

**CIP R&D Plan** – Lead writer: "Entry and Access Portals" theme for the <u>Critical Infrastructure Protection R&D</u> <u>Plan</u>, for the Office of Science & Technology Policy, the White House, 2004.

Excelerate Technology, Inc., Boston, MA – Member of the Technical Advisory Board, 2001-2004.

- SIA-ITRS Semiconductor Industry Association, International Technology Roadmap for Semiconductors, Member: U.S. Domestic Yield Enhancement Technology Working Group, 2002-2003. Member: U.S. Defect Reduction Technology Working Group, 1999-2001.
- SIA-NTRS Semiconductor Industry Association, National Technology Roadmap for Semiconductors, Member: Defect Reduction Technology Working Group, 1997-1998.

**FBI SWGIT** – Member, Federal Bureau of Investigation's Scientific Working Group on Imaging Technologies, Quantico, Virginia, 1998-2000.

#### **Conference / Committee**

**General Chair**: Organizer, NEUWAVE-4, 4<sup>th</sup> Workshop on Neutron Wavelength Dependent Imaging, Gatlinburg, TN, October 2-5, 2011.

**International Program Committee Member** – 2<sup>nd</sup> International Topical Meeting on Optical Sensing and Artificial Vision, 12-15 May, 2008, St. Petersburg, Russia.

**Ph.D. Committee Member** – ORNL Mentor and Doctoral Committee for Vincent Paquit, University of Burgundy, Le Creusot, France, December 2008.

**International Program Committee Member / Conference Chair** – International Symposium on Visual Computing, Lake Tahoe, Nevada, 2005-07.

**International Program Committee Member / Conference Chair**- International Topical Meeting on Optical Sensing and Artificial Vision, St. Petersburg, Russia, October 19-21, 2004

**Ph.D. Committee Member** – ORNL Mentor and Doctoral Committee for Pierrick Bourgeat, University of Burgundy, Le Creusot, France, July 2004.

ORNL - Service to the Oak Ridge National Laboratory, 1998-present.

Chairman, UT-Battelle United Way Campaign, 2017. Committee Member of the ORNL Named Fellowship Selection Committee, 2017. Co-Chair, UT-Battelle United Way Campaign, 2016. Member, Innovation and Commercialization Committee, UT-Battelle Awards Night 2016. **ORNL Technology Innovation Program** (TIP) Selection Committee, 2015-2016. Chairman of the Wigner Fellow Selection Committee, 2015-2016. Member of the Wigner Fellow Selection Committee, 2004-2014. Chairman, Technical Support Award Committee, UT-Battelle Awards Night 2011. Chairman, Engineering Award Committee, UT-Battelle Awards Night 2010. FY 2011 LDRD Initiative Review Committee Member, Global Security, 2010. FY 2010 LDRD Initiative Review Committee Member, Advanced Energy Systems, 2009 Chairman, Engineering Committee, UT-Battelle Awards Night 2009. Lead Writer: Engineering Science and Technology Division Strategic Plan Revision for 2005-2007. Invited Member of the National Security Directorate Strategic Advisory Group, 2007-2008. Vice-Chairman of the Oak Ridge National Laboratory Corporate Fellow Committee, 2006-2007. Engineering Sciences Directorate Representative, Invention Disclosure Review Committee (IDRC), 2004-2006. Member of the Oak Ridge National Laboratory Seed Money Proposal Review Committee (PRC), 2001-2002. Member of the Oak Ridge National Laboratory Inventor's Forum Executive Committee, 1998-2000.

SPIE (Elected to rank of Fellow, March 2001) - The International Society for Optics and Photonics, 1989 - present.

Associate Editor for Vision Systems: 2005-present, SPIE Journal of Electronic Imaging, Editor-in-Chief, Prof. Gaurav Sharma, University of Rochester.

**Conference Co-Chair**: 2006, SPIE Conference on Data Analysis and Modeling for Patterning Control III, part of the SPIE International Symposium on Microlithography, San Jose, CA

**Conference Co-Chair**: 2005, SPIE Conference on Data Analysis and Modeling for Process Control II, part of the SPIE International Symposium on Microlithography, San Jose, CA

**Conference Chairman / Creator**: 2004, SPIE Conference on Data Analysis and Modeling for Process Control I, part of the SPIE International Symposium on Microlithography, Santa Clara, CA

**Conference Chairman / Creator:** 2003, SPIE Conference on Process and Materials Characterization and Diagnostics in IC Manufacturing II, part of the 1<sup>st</sup> Annual International Symposium on Advanced Microelectronic Manufacturing, Santa Clara, CA

**Conference Chairman / Creator:** 2002, SPIE Conference on Process Characterization and Diagnostics in IC Manufacturing I, part of the 27<sup>th</sup> Annual International Symposium on Microlithography, Santa Clara, CA **Committee Member:** 2003, SPIE Conference on Microsystems Engineering: Metrology and Inspection III, part of SPIE's International Symposium on Optics and Lasers in Metrology International Congress Center Munich, Munich, Germany, 23-26 June 2003.

**Committee Member:** 2003, SPIE Conference on Wavelet Applications in Industrial Processing, International Symposium on Intelligent Systems and Advanced Manufacturing, part of Photonics East, Rhode Island Convention Center, Providence, Rhode Island, 27-31 October 2003.

**Program Chairman:** 2001, Program on Micro-engineering / Manufacturing, SPIE International Symposium on Lasers and Applications in Science & Technology, San Jose, CA

**Conference Chairman:** 2001, Conference on Metrology-based Control for Micro-manufacturing, SPIE International Symposium on Lasers and Applications in Science & Technology, San Jose, CA.

**Conference Chairman:** 1999-2000 Conference on Machine Vision Applications in Industrial Inspection, SPIE International Symposium on Electronic Imaging, San Jose Convention Center, San Jose, CA **Committee Member:** 1996-1998, 2001-2002 Conference on Machine Vision Applications in Industrial Inspection, SPIE International Symposium on Electronic Imaging, San Jose Convention Center, San Jose, CA

IEEE (Elected to rank of Fellow, January 2012) – The Institute of Electrical and Electronics Engineers, 1999 - present.
General Chair, 4<sup>th</sup> Annual Future of Instrumentation and Internet Workshop, IEEE Instrumentation and Measurement Society, National Rural Electric Cooperative Association, Arlington, VA, May 4-6, 2015.
General Chair, 3<sup>rd</sup> Annual Future of Instrumentation International Workshop, IEEE Instrumentation and Measurement Society, Gatlinburg, Tennessee, October 8-11 2012.

**General Chair**, 2<sup>nd</sup> Annual Future of Instrumentation International Workshop, IEEE Instrumentation and Measurement Society, Oak Ridge, Tennessee, November 7-8, 2011.

**Session Chairman**, 33<sup>rd</sup> Annual International IEEE EMBS Conference, Retinal Image Analysis II, Boston, MA, August 30 - September 3, 2011.

**General Chair**, Future of Instrumentation International Workshop, IEEE Instrumentation and Measurement Society, Oak Ridge, Tennessee, November 8-9, 2010.

**Co-Sponsor**, 3<sup>rd</sup> Annual ORNL Biomedical Science and Engineering Conference: Image Informatics and Analytics in Biomedicine, in Cooperation with IEEE EMBS, March 2011.

**Co-Sponsor**, 2<sup>nd</sup> Annual ORNL Biomedical Science and Engineering Conference: Biomedical Research and Analysis in Neuroscience (BRAiN), in Cooperation with IEEE EMBS, May 2010.

**Co-Sponsor**, 1<sup>st</sup> Annual ORNL Biomedical Science and Engineering Conference: Exploring the Intersections of Interdisciplinary Biomedical Research, in Cooperation with IEEE EMBS, March 2009.

**Reviewer,** IEEE Transactions on Image Processing, Transactions on Signal Processing, Transactions on Medical Imaging

**Vice-Chairman and Founding Officer** of the East Tennessee Chapter of the Engineering in Medicine and Biology Society (EMBS), 2006-2008

**Program Committee Member** for the IEEE Workshop on Applications of Computer Vision, WACV 2008, Colorado, January 2008.

**Co-Chair, International Scientific Committee**, 8<sup>th</sup> International Conference on Quality Control by Artificial Vision, Le Creusot, France, May 2007

**Program Committee Member** – IEEE, EURASIP 8th Annual Symposium on Advanced Concepts for Intelligent Vision Systems (ACIVS), University of Antwerp, Antwerp, Belgium, 2006-2007.

**Reviewer**, IEEE Nuclear Science Symposium and Medical Imaging Conference, Wyndham El Conquistador Resort, Puerto Rico, October 23-29, 2005,

**Co-Chair, International Scientific Committee**, 2005, Quality Control by Artificial Vision, Nagoya Congress Center, Nagoya, Japan

**Conference Organizer and General Chair:** 2003, 6<sup>th</sup> International Conference on Quality Control by Artificial Vision, Gatlinburg, Tennessee, USA (in cooperation with SPIE and SME)

**Co-Chair, International Scientific Committee:** 2001, Quality Control by Artificial Vision, Le Creusot, France **Committee Member:** 1998-2000, IEEE Workshop on Computer Vision Beyond the Visible Spectrum: Methods and Applications

### **ISSUED PATENTS**

- **Tobin**, K.W., Karnowski, T.P., Chaum, E., "Method and System for the Diagnosis of Disease Using Retinal Image Content and an Archive of Diagnosed Human Patient Data," UT-Battelle, LLC, Invention Disclosure No. 1596.1, U.S. Patent No. 8,503,749, August 6, 2013.
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# **INVENTION DISCLOSURES**

- Price, J.R., Paquit, V., **Tobin**, K.W., "Improved Device for Assisted Venipuncture," UT-Battelle, LLC, Invention Disclosure No. 1300002067, March 31, 2008.
- **Tobin**, K.W., Karnowski, T.P., "A Method for Directed Indexing of Image Databases for Content-based Retrieval Applications", UT-Battelle, LLC, Invention Disclosure No. 1151, September 2002.
- Ferrell, R.K., **Tobin**, K.W., Karnowski, T.P., "Focus-of-Attention with Database Retrieval Comparison for Operator Threat Assessment X-Ray Screening," UT-Battelle, LLC, Invention Disclosure No. 1413, May 2004.
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- Karnowski, T.P., Bingham, P.R., **Tobin**, K.W., and Simpson, J.T., "Through-the-Pellicle Heterodyne Mask Inspection", UT-Battelle, LLC, Invention Disclosure No. 1311, August 13, 2003.
- Karnowski, T.P., **Tobin**, K.W., "Content-based Pattern Retrieval", UT-Battelle, LLC, Invention Disclosure No. 1227C, DOE S-101,813, January 2003.
- Gleason, S.S., **Tobin**, K.W., "A Method for Geo-spatial Image Segmentation using Fractal Encoding and Exemplars", UT-Battelle, LLC, Invention Disclosure No. 1150, September 2002.

# COPYRIGHTS

- UT-BATTELLE Copyright Docket Number 40000092, "Retina Image Screening and Analysis Software, Version 2.0," T.P. Karnowski, L. Giancardo, D. Aykac, K.W. **Tobin**
- UT-BATTELLE Copyright Docket Number 40000031, "Automated Image Retrieval (AIR) Version 1.0," Creators: T. P. Karnowski, R. K. Ferrell, K. W. **Tobin**
- UT-BATTELLE Copyright Docket Number 40000032, "Automated Image Retrieval (AIR) Version 2.0," Creators: T. P. Karnowski, R. K. Ferrell, K. W. **Tobin**
- UT-BATTELLE Copyright Docket Number 40000053, "Intelligent Data Management (IDM) for a Content Based Image Retrieval," Creators: T. P. Karnowski, K. W. **Tobin**
- UT-BATTELLE Copyright Docket Number 40000054, "Defect Mask Encoder (DME) for a Content-Based Image Retrieval System," Creators: J. R. Price, K. W. **Tobin**

# NATIONAL / INTERNATIONAL AWARDS AND RECOGNITION

- <u>Battelle Distinguished Inventor</u>, Battelle Memorial Institute, 2015.
- Elected to the grade of <u>Fellow of IEEE</u>, The Institute of Electrical and Electronics Engineers, January 2012.
- <u>American Telemedical Association (ATA) Innovation Award</u> for development of the TRIAD Ocular Telehealth Network, April 2011.
- Southeast Region <u>Federal Laboratory Consortium</u> Award for "TRIAD (Telemedical Retinal Image Analysis and Diagnosis)," recognition for Excellence in Technology Transfer, October 2010.
- R&D Magazine's <u>R&D 100 Award</u> for applied research in the development of the Telemedical Retinal Image Analysis and Diagnosis (TRIAD) System and Technology, November 2010.
- Southeast Region <u>Federal Laboratory Consortium</u> Award for "Automated Image Retrieval: Semiconductor-Specific Image Retrieval Method and System", recognition for Excellence in Technology Transfer, August 2007.
- SPIE <u>Symposium on Medical Imaging</u>, Conference on Visualization, Image-Guided Procedures, and Display, "Best Poster" of session and "Cum Laude" poster, February 2006.
- National <u>Federal Laboratory Consortium</u> Award for "MicroCAT Small Animal Imaging System ", recognition for Excellence in Technology Transfer, May 2005.
- Southeast Region <u>Federal Laboratory Consortium</u> Award for "MicroCAT Small Animal Imaging System", recognition for Technology Transfer Project of the Year, September 2004.

- Elected to the grade of <u>Senior Member of IEEE</u>, The Institute of Electrical and Electronics Engineers, August 2004.
- National <u>Federal Laboratory Consortium</u> Award for "Automated Image Retrieval System for Semiconductor Yield Improvement", recognition for Excellence in Technology Transfer, May 2003.
- Southeast Region <u>Federal Laboratory Consortium</u> Award for "Automated Image Retrieval Technology", recognition for Excellence in Technology Transfer, January 2003.
- R&D Magazine's <u>R&D 100 Award</u> for applied research in the development of the Defect Source Identifier Automated Image Retrieval (DSI-AIR) System for Semiconductor Image Data Management, 2002.
- National <u>Federal Laboratory Consortium</u> Award for Excellence in Technology Transfer, "Direct-to-Digital Holography for High-Speed, High Resolution Defect Inspection", March 2002.
- Southeast Region <u>Federal Laboratory Consortium</u> Award for "Direct-to-Digital Holography for High-Speed, High Resolution Defect Inspection", recognition for the new category of Excellence in Technology Transfer Award of the Year, November 2002.
- Elected to the grade of <u>Fellow of SPIE</u>, The International Society for Optics and Photonics, March 2001.
- Tennessee Academy of Science, <u>Industrial Scientist of the Year</u>, for Leadership and Scientific Contributions to Semiconductor Metrology, November 2000.
- <u>American Museum of Science and Energy</u> Award for Marketed Technology for the "Spatial Signature Analysis Software System", May 1998.
- National <u>Federal Laboratory Consortium</u> Award for Excellence in Technology Transfer, "Spatial Signature Analysis System for Semiconductor Yield Improvement", March 1998.
- Southeast Region <u>Federal Laboratory Consortium</u> Award for Excellence in Technology Transfer, "Spatial Signature Analysis System for Semiconductor Yield Improvement", March 1998.

# OAK RIDGE NATIONAL LABORATORY AWARDS

- UT-Battelle, LLC, <u>Awards Night Recognition</u> for Excellence in Technology Transfer for Successful Technology Transfer of a Creative and Innovative Application of ORNL Technology to Solve Important High-Impact Problems in Public Health Care, September 2010.
- ORNL <u>Laboratory Directed Research and Development Poster Day</u> "Best Poster" for "Improving Iris Recognition," October 2006.
- UT-Battelle, LLC, <u>Awards Night Director's Award</u> for Outstanding Team Accomplishment in Science and Technology, for Successful Development of a Content-based Image Retrieval System for Semiconductor Yield Improvement October 2002.
- UT-Battelle, LLC, <u>Awards Night Recognition</u> for Outstanding Engineering Development Team Accomplishment, for Successful Development of a Content-based Image Retrieval System for Semiconductor Yield Improvement October 2002.
- UT-Battelle, LLC, <u>Awards Night Recognition</u> for Distinguished Engineer (Individual) for Developing an Internationally Recognized Program in Computer Vision and Semiconductor Metrology, November 2001.
- UT-Battelle, LLC, <u>Awards Night Recognition</u> for Engineering Development by a Team for Development of a Direct-to-digital Holographic System for Metrology and Inspection, November 2001.
- Oak Ridge National Laboratory <u>Significant Event Award</u> for "Development of ORNL Automated Image Retrieval Technology", September 2001.
- Oak Ridge National Laboratory <u>Significant Event Award</u> for "Establishing a unique and precedent-setting, three way working relationship in the semiconductor industry between ORNL, International SEMATECH, and Applied Materials, Inc.", June 2000.

- Lockheed Martin Energy Systems, Inc. <u>Awards Night Recognition</u> for Development Accomplishment for Imaging Colorimetry Technology/System, March 1999.
- Lockheed Martin Energy Systems, Inc. <u>Awards Night Recognition</u> for Technology Achievement in support of the semiconductor industry, March 1998.
- Oak Ridge National Laboratory <u>Significant Event Award</u> for delivery of Spatial Signature Analysis technology to SEMATECH, March 1997.

# **BOOKS / CHAPTERS / EDITOR**

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Singh, B., **Tobin**, K.W., Guest Editor for special Section of the <u>Journal of Microlithography</u>, <u>Microfabrication</u>, and <u>Microsystems</u>, SPIE, Vol. 5, No.2, April 2006.

Emami, I., Ausschnitt, C. P., and **Tobin**, K.W., Chair/Editor, <u>Data Analysis and Modeling for Process Control II</u>, Proceedings of the SPIE, Vol. 5755, March 2005.

**Tobin**, K.W., Lead Writer, "Entry and Access Portals," <u>National Plan for Research and Development in Support of</u> <u>Critical Infrastructure Protection</u>, The Executive Office of the President, Office of Science and Technology Policy, 2004.

**Tobin,** K.W., Mereaudeau, F., Costa, Luciano de Fontoura, Guest Editor for special Section of the <u>Journal of Electronic</u> <u>Imaging</u> on "Quality Control by Artificial Vision", SPIE, Vol. 13, No. 3, July 2004.

**Tobin,** K.W., Emami, I, Chair/Editors, <u>Data Analysis and Modeling for Process Control I</u>, Proceedings of the SPIE, Vol. 5378, May 2004.

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**Tobin**, K.W., Emami, I., Chair/Editors, <u>Process and Materials Characterization and Diagnostics in IC Manufacturing II</u>, Proceedings of the SPIE Vol. 5041, May 2003.

**Tobin,** K.W., Starikov, A., Chair/Editors, <u>Design, Process Integration, and Characterization for Microelectronics</u>, Proceedings of the SPIE Vol. 4692, March 2002.

**Tobin**, K.W., Lakhani, F., Chair/Editors, <u>Metrology-based Control for Micro-manufacturing</u>, Proceedings of the SPIE, Vol. 4275, July 2001.

**Tobin**, K.W., Chair/Editor, <u>Machine Vision Applications in Industrial Inspection VIII</u>, Proceedings of the SPIE, Vol. 3966A and B, July 2000.

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**Tobin,** K.W., Neiberg, L., "Metrology Data Management and Information Systems", (Alain C. Diebold, Editor) <u>Handbook of Silicon Semiconductor Metrology</u>, Alain Diebold, Editor, Marcel Dekker, Inc., New York, New York, 2001.

**Tobin**, K.W., Editorial Advisory Board for Engineering/Machine Vision (Joseph P. Hornak, Editor), <u>The Encyclopedia of Imaging Science and Technology</u>, Vol. 1-2, John Wiley & Sons, Inc., New York, 2002.

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**Tobin**, K.W., Chang, N., Chair/Editors, <u>Machine Vision Applications in Industrial Inspection VII</u>, Proceedings of the SPIE, Vol. 3652, July 1999.

# NATIONAL / INTERNATIONAL INVITED PRESENTATIONS

**Tobin, K.W.**, "IoT and the Electric Grid," Dept. of Commerce NTIA Workshop Fostering the Advancement of the Internet of Things, USPTO Office, Alexandria, Virginia, September 1, 2016.

**Tobin, K.W.**, "Electronics, Sensors, and Controls for the Internet of Things," HAVI Global Solutions, Packaging Technology and Integrated Solutions: Future of Packaging Annual Meeting, National Transportation Research Center, Knoxville, Tennessee, May 24, 2016.

**Tobin, K.W.**, "The Energy Revolution in an Interconnected World," Keynote Speaker, Oklahoma Research Day, Northeastern State University, March 11, 2016.

**Tobin, K.W.**, "Electronics, Sensors, and Controls for the Energy Challenge," Global Institute of Sustainability, Arizona State University, January 27, 2016.

**Tobin, K.W.**, "Science and Technology Research for the Energy Challenge," ORNL Challenge Opportunity, Duke University, October 7, 2015.

**Tobin,** K.W., "Advanced Material Characterization with Neutron Imaging," Neutron Characterization of Additively Manufactured Components Workshop, Oak Ridge National Laboratory, Feb 25-26, 2015.

**Tobin**, K.W., "Electronics, Sensing, and Communications Research for Energy Efficiency, Resiliency, and Security," Idaho National Laboratory, Idaho Falls, Idaho, September 25, 2014.

**Tobin,** K.W., "ORNL Sensing and Communications Research for City System Design," Oak Ridge National Laboratory Extended Leadership Team Meeting, July 28, 2014.

**Tobin,** K.W., "Electronics, Sensing, and Communications Research for City System Design," Keynote Speaker - NETL Crosscutting Research Review Meeting, Pittsburg, Pennsylvania, May 19-23, 2014.

**Tobin,** K.W., "The Impact of Sensing and the Internet-of-Things on the City as a System," Urban Dynamics Institute Seminar Series, Oak Ridge National Laboratory, May 5, 2014. , May 20, 2014.

**Tobin**, K.W., "Biomedical Technology Development and Maturation at ORNL," Venture Match Seminar: Medical Device and Imaging, The Proton Therapy Center, Knoxville, Tennessee, February 25, 2014.

**Tobin,** K.W., "Electrical and Electronics Systems Research: High Resolution Neutron Microscopy," Center for Intelligent Systems and Machine Learning, Department of Electrical Engineering and Computer Science, *University of Tennessee*, January 31, 2014.

**Tobin**, K.W., "Sensor Technology, Instrumentation, and Analysis for Energy Research," UC Davis / McClellan Nuclear Research Center, Sacramento, California, June 25, 2013.

**Tobin**, K.W., Bilheux, H., Herwig, K., Keener, S., Davis, L., Geoghegan, C., Gallmeier, F., Popova, I., "VENUS: Versatile Neutron Imaging Instrument at the Spallation Neutron Source," 5<sup>th</sup> Neutron Wavelength Dependent Imaging Workshop, Lund, Sweden, April 21-24, 2013.

**Tobin**, K.W., "Sensors and Sensor Networks for a Sustainable Environment," Sustainable Eagle Ford Shale Community Infrastructure Challenges and Solutions Workshop, *Texas A&M*, Kingsville, Texas, April 10, 2013.

**Tobin**, K.W., "Telemedical Retinal Image Analysis and Diagnosis (TRIAD) and the R&D 100 Award," Oak Ridge Institute for Continuous Learning (ORICL), *Roane State Community College*, Oak Ridge, TN, February 23, 2011.

**Tobin**, K.W. "Multi-Disciplinary Research and Development in the Field of Applied Computer Vision at the Oak Ridge National Laboratory," ECE Graduate Seminar Series, Electrical and Computer Engineering, *Purdue University*, October 21, 2009.

**Tobin,** K.W., Chaum, E., Karnowski, T.P., Li, Y., Giancardo, L., Aykac, D., "A Telemedicine Approach to the Reduction of Blindness from Diabetic Retinopathy," The Technical Society of Knoxville, Crown Plaza, Knoxville, TN, June 28, 2009.

**Tobin**, K.W., Chaum, E., Giancardo, L., Karnowski, T.P., Li, Y, "A Telemedicine Network for the Automated Diagnosis of Diabetic Retinopathy," SAOT Retina Image Processing Workshop 2009, *Friedrich-Alexander University*, Erlangen, Germany, March 9-10, 2009.

**Tobin**, K.W, Chaum, E., Giancardo, L., Karnowski, T.P., "Using Image Content to Diagnose and Stratify Diabetic Retinopathy," Asilomar Conference of Signal, Systems, and Computers; General Session on Biomedical Signal and Image Processing, Pacific Grove, California, Oct. 26-29, 2008.

**Tobin**, K.W., "Applied Research and Development at the Oak Ridge National Laboratory," Center for Advanced Computer Studies Distinguished Lecture Series, *University of Louisiana*, Lafayette, Louisiana, September 26, 2008.

**Tobin**, K.W., "A History of Applied Research and Development through the Measurement Science and Systems Engineering Division at the Oak Ridge National Laboratory," Friends of ORNL, Oak Ridge, Tennessee, September 17, 2008.

**Tobin,** K.W., "Computer Vision Research and Development at the Oak Ridge National Laboratory," Department of Mechanical and Nuclear Engineering, *Pennsylvania State University*, State College, Pennsylvania, March 20, 2008

**Tobin**, K.W., Abdelrahman, M., Chaum, E., Govindasamy, V.P., Karnowski, T.P., "A Probabilistic Framework for Content-Based Diagnosis of Retinal Disease," Electrical and Computer Engineering Colloquium, *Tennessee Technological University*, Cookeville, Tennessee, November 6, 2007.

**Tobin**, K.W., Bingham, P.R., Price, J.R., "Optical Spatial Heterodyned Interferometry and Inspection of Micro-Electro-Mechanical Systems," 8<sup>th</sup> International Conf. on Quality Control by Artificial Vision, *Proceedings of SPIE*, Vol.6356, Le Creusot, France, May 23-25, 2007.

**Tobin**, K.W., "Biomedical Imaging and Computer Vision at the Oak Ridge National Laboratory," Preclinical Research & Development, *Siemens Medical Solutions USA*, *Inc.*, January 29, 2007.

**Tobin**, K.W., "Biomedical Imaging and Informatics and the Oak Ridge National Laboratory," *Vanderbilt University Institute of Imaging Science*, Nashville, Tennessee, January 17, 2007.

**Tobin,** K.W., Chaum, E., Karnowski, T.P., Govindasamy, V.P., "An Image-Based Method for Rapid Screening of Diabetic Retinopathy," Engineering Colloquium Lecture, Electrical Engineering Department, *Norfolk University*, Norfolk, Virginia, October 27, 2005.

**Tobin,** K.W., Chaum, E., Karnowski, T.P., Govindasamy, V.P., "An Image-Based Method for Rapid Screening of Diabetic Retinopathy," *The Technical Society of Knoxville*, Crowne Plaza Hotel, Knoxville, Tennessee, October 24, 2005.

**Tobin,** K.W., "Small Animal Image Analysis and Data Management for CT and SPECT," Symposium on Nanotechnology Applications in Medicine, *Hamilton Eye Institute*, Memphis, TN, September 28, 2005.

**Tobin**, K.W., Bingham, P.R., "Optical Spatial Heterodyned Interferometry for Applications in Semiconductor Inspection and Metrology," International Conference on Lasers, Applications, and Technologies, *Proceedings of SPIE*, Vol. 6162, St. Petersburg, Russia, May 11-15, 2005.

**Tobin**, K.W., "Applied Computer Vision R&D at the Oak Ridge National Laboratory," Fall Colloquia, Computer Science and Engineering Department, and Northern Nevada IEEE, *University of Nevada*, Reno, Nevada, Oct. 18, 2004.

**Tobin**, K.W., "Applied Computer Vision R&D at the Oak Ridge National Laboratory," School of Science and Technology Colloquium, Electrical Engineering Department, Norfolk State University, and Electrical and Computer Engineering Department, *Old Dominion University*, Norfolk, Virginia, Sept. 30-Oct.1, 2004.

**Tobin**, K.W., Bingham, P.R., Bennett, M.H., Marmillion, P. "Spatial Heterodyned Interferometry for High-Throughput Inspection and Metrology of Phase Shifting Masks", *Invited Speaker at IEEE Lithography Workshop*, Whistler, British Columbia, Canada, July 26-30, 2004.

**Tobin**, K.W., "Optical Interferometric Imaging for Inspection and Metrology," International Speakers Colloquium, *University of Burgundy*, Dijon, France, July 8, 2004.

**Tobin,** K.W., Bingham, P.R., Price, J.R., Bourgeat, P., Hansen, G., "Optical Interferometric Imaging for Inspection and Metrology," ECE Graduate Seminar Series, Electrical and Computer Engineering, *Purdue University*, October 30, 2003.

**Tobin**, K.W., "Image Data Management and Analysis in Semiconductor Wafer Manufacturing for Rapid Yield Learning", *East Tennessee Chapter of the IEEE*, CTI, Inc., Knoxville, TN, March 20, 2002.

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**Tobin**, K.W., Bingham, P.R., Price, J.R., and Bennett, M.H., "An Application of Image Retrieval Technology to Sidewall Structure Estimation from Top-down SEM Imagery", *13<sup>th</sup> Annual Scientific Meeting of Scanning Microscopy*, Roosevelt Hotel, New York, New York, May 5-7, 2001.

**Tobin**, K.W., Karnowski, T.P., Arrowood, L.F., Ferrell, R.K., Goddard, J.S., "Content-based Image Retrieval for Semiconductor Process Characterization", *IEEE Quality Control by Artificial Vision*, Le Creusot, France, May 2001.

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**Tobin**, K.W., Karnowski, T.P., and Lakhani, F., "New Trends in Integrated Yield Management", *Solid State Technology's Metrology 2000*, San Jose, CA, May 1-2, 2000.

**Tobin**, K.W., Karnowski, T.P., Gleason, S.S., Jensen, D., Lakhani, F., "Integrated Yield Management", *196<sup>th</sup> Meeting of the Electrochemical Society, Inc.*, Oct. 17-22, Honolulu, Hawaii, 1999.

**Tobin**, K.W., Karnowski, T.P., and Lakhani, F., "The Analysis and Classification of Spatial Patterns in Wafermap Data", University of Tennessee, Department of Statistics, *College of Business Administration*, Knoxville, TN, Oct. 8, 1999.

**Tobin**, K.W., Karnowski, T.P., Gleason, S.S., Gee, T.F., Jensen, D., Lakhani, F., "The Analysis and Classification of Spatial Patterns on Wafermap Data", Spatial Statistics and Pattern recognition, *16<sup>th</sup> Statistical Methods Symposium*, SEMATECH, Austin, Texas, May 18-20, 1999.

**Tobin**, K.W., Karnowski, TP., Gleason, S.S., Jensen, D., Lakhani, F., "Using Historical Wafermap Data for Automated Yield Analysis", *45<sup>th</sup> Annual International Symposium of the American Vacuum Society*: Manufacturing Science and Technology, Nov. 2-6, Baltimore, Maryland, 1998.

**Tobin**, K.W., Karnowski, T.P., Gleason, S.S., F. Lakhani, "Defect Data Management in the Semiconductor Manufacturing Environment", *Society of Manufacturing Engineers*, Applied Machine Vision 98, Nashville, TN, May 18-22, 1998.

**Tobin**, K.W., Gleason, S.S., Karnowski, T.P., Sari-Sarraf, H., "Semiconductor Defect Data Reduction for Process Automation and Characterization", Tenth International Forum Process Analytical Chemistry - IFPAC<sup>SM</sup>, Orlando, Florida, January 21-24, 1996.

**Tobin**, K.W., "Applying Photonics Technologies in Industrial and Commercial Systems: Machine Vision For Industrial Inspection and Automation", *SPIE International Symposium on Optical Engineering in Aerospace Sensing*, Orlando, Florida, April 4-8, 1994.

**Tobin**, K.W., "Machine Vision for Industrial Inspection and Automation", Optical Diagnostics in Manufacturing and Process Control, *DOE Joint Industry/National Laboratory Symposium*, Oak Ridge, TN, December, 1993.

**Tobin**, K.W., "Automated Inspection Methods: Machine Vision Inspection of Thick-Film Ceramic Substrates", Oak Ridge Institute for Science and Education, DOE Traveling Lecturer Program, Mechanical Engineering Dept., Virginia Tech, Blacksburg, VA, April, 1993.

### PUBLICATIONS

**Tobin**, K.W., Fowler, K., Fuhr, P., McIntyre, T., "The Future of Instrumentation," <u>The IEEE Instrumentation and</u> <u>Measurement Magazine</u>, April 2013.

Giancardo, L., Meriaudeau, F., Karnowski, T.P., Li, Garg, S., **Tobin**, K.W., Chaum, E., "Exudate-based Diabetic Macular Edema Detection in Fundus Images Using Publicly Available Datasets," <u>Medical Image Analysis</u>, Vol. 16, No. 1, January 2012.

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